WHAT IS CLAIMED IS:

- 1. A thermally conductive material for removing the heat dissipated by an integrated circuit, the thermally conductive material comprising a diamondoid.
 - 2. The thermally conductive material of claim 1, wherein the diamondoid comprises a diamondoid-containing material.
- 10 3. The thermally conductive material of claim 1, wherein the diamondoid comprises a derivatized diamondoid.
 - 4. The thermally conductive material of claim 1, wherein the diamondoid comprises an underivatized diamondoid.

5. The thermally conductive material of claim 1, wherein the diamondoid is a lower diamondoid.

- 6. The thermally conductive material of claim 1, wherein the diamondoid is a higher diamondoid.
 - 7. The thermally conductive material of claim 6, wherein the diamondoid is selected from the group consisting of tetramantane, pentamantane, hexamantane, heptamantane, octamantane, nonamantane, decamantane, and undecamantane.
 - 8. The thermally conductive material of claim 1, wherein the material is a film.
 - 9. The thermally conductive material of claim 1, wherein the material is a fiber.
- 30 10. The thermally conductive material of claim 2, wherein the diamondoid-containing material is selected from the group consisting of a diamondoid-containing polymer, a diamondoid-containing sintered ceramic, a diamondoid ceramic composite, a CVD diamondoid film, and a self-assembled diamondoid film.

11. The thermally conductive material of claim 10, wherein the diamondoid content of the thermally conductive material ranges from about 1 to 100 percent by weight for the diamondoid-containing polymer, about 1 to 99.9 percent by weight for the diamondoid-containing sintered ceramic, about 1 to 100 percent by weight for the CVD diamondoid film, and about 1 to 99.99 percent by weight for the self-assembled diamondoid film.

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- 12. The thermally conductive material of claim 1, wherein the thermal conductivity of the material is at least 200 W/m K.
- 13. The thermally conductive material of claim 1, wherein the thermal conductivity of the material is at least 500 W/m K.
- 14. The thermally conductive material of claim 1, wherein the thermal conductivity of the material is at least 1,000 W/m K.
 - 15. A low-k material for electrically isolating the interconnection lines and vias of an integrated circuit, the low-k material comprising a diamondoid.
- 20 16. The low-k material of claim 15, wherein the diamondoid comprises a diamondoid-containing material.
 - 17. The low-k material of claim 15, wherein the diamondoid comprises a derivatized diamondoid.
 - 18. The low-k material of claim 15, wherein the diamondoid comprises an underivatized diamondoid.
 - 19. The low-k material of claim 15, wherein the diamondoid is a lower diamondoid.
 - 20. The low-k material of claim 15, wherein the diamondoid is a higher diamondoid.

- 21. The low-k material of claim 20, wherein the diamondoid is selected from the group consisting of tetramantane, pentamantane, hexamantane, heptamantane, octamantane, nonamantane, decamantane, and undecamantane.
- 5 22. The low-k material of claim 15, wherein the material is a film.
 - 23. The low-k material of claim 15, wherein the material is a fiber.
- 24. The low-k material of claim 16, wherein the diamondoid-containing material is selected from the group consisting of a diamondoid-containing polymer, a diamondoid-containing sintered ceramic, a diamondoid ceramic composite, a CVD diamondoid film, and a self-assembled diamondoid film.
- 25. The low-k material of claim 24, wherein the diamondoid content of the low-k
 material ranges from about 1 to 100 percent by weight for the diamondoid-containing
 polymer, about 1 to 99.9 percent by weight for the diamondoid-containing sintered ceramic,
 about 1 to 100 percent by weight for the CVD diamondoid film, and about 1 to 99.99 percent
 by weight for the self-assembled diamondoid film.
- 26. The low-k material of claim 15, wherein the dielectric constant of the material is less than about 4.
 - 27. The low-k material of claim 15, wherein the dielectric constant of the material is less than about 3.
 - 28. The low-k material of claim 15, wherein the dielectric constant of the material is is less than about 2.
- 29. A field emission device having a cathode, wherein the cathode comprises a diamondoid.

30. The field emission device of claim 29, wherein the diamondoid comprises a diamondoid-containing material.

- 31. The field emission device of claim 29, wherein the diamondoid comprises a derivatized diamondoid.
- 5 32. The field emission device of claim 29, wherein the diamondoid comprises an underivatized diamondoid.
 - 33. The field emission device of claim 29, wherein the diamondoid is a lower diamondoid.
 - 34. The field emission device of claim 29, wherein the diamondoid is a higher diamondoid.

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- 35. The field emission device of claim 34, wherein the diamondoid is selected from the group consisting of tetramantane, pentamantane, hexamantane, heptamantane, octamantane, nonamantane, decamantane, and undecamantane.
 - 36. The field emission device of claim 29, wherein the material is a film.
- 20 37. The field emission device of claim 29, wherein the material is a fiber.
 - 38. The field emission device of claim 30, wherein the diamondoid-containing material is selected from the group consisting of a diamondoid-containing polymer, a diamondoid-containing sintered ceramic, a diamondoid ceramic composite, a CVD diamondoid film, and a self-assembled diamondoid film.
 - 39. The field emission device of claim 29, wherein the diamondoid content of the cathode ranges from about 1 to 100 percent by weight for the diamondoid-containing polymer, about 1 to 99.9 percent by weight for the diamondoid-containing sintered ceramic, about 1 to 100 percent by weight for the CVD diamondoid film, and about 1 to 99.99 percent by weight for the self-assembled diamondoid film.

- 40. The field emission device of any of claims 29 through 39, wherein the electron affinity of the cathode is negative.
- 41. The field emission device of any of claims 29 through 39, wherein the electron affinity of the cathode is less than about 3.0 eV.
 - 42. The field emission device of any of claims 29 through 39, further including an anode positioned adjacent to the cathode, and a power supply for supplying a potential difference between the anode and the cathode.

- 43. The field emission device of any of claims 29 through 39, where the potential difference that is applied between the anode and the cathode is less than about 10 volts.
- 44. The field emission device of any of claims 29 through 39, wherein the diamondoid surface surface comprises carbon atoms that are substantially sp³-hybridized.
 - 45. The field emission device of any of claims 29 through 39, wherein the diamondoid surface is derivatized such that the surface comprises both sp² and sp³-hybridization.
- 20 46. A capacitor having a dielectric layer positioned between a first electrode and a second electrode, wherein the dielectric layer comprises a diamondoid-containing material.
 - 47. The capacitor of claim 46, wherein the diamondoid comprises a derivatized diamondoid.

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- 48. The capacitor of claim 46, wherein the diamondoid comprises an underivatized diamondoid.
- 49. The capacitor of claim 46, wherein the diamondoid is a lower diamondoid.

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50. The capacitor of claim 46, wherein the diamondoid is a higher diamondoid.

- 51. The capacitor of claim 50, wherein the diamondoid is selected from the group consisting of tetramantane, pentamantane, hexamantane, heptamantane, octamantane, nonamantane, decamantane, and undecamantane.
- 5 52. An integrated circuit device passivated by a diamondoid-containing material.
 - 53. The integrated circuit device of claim 52, wherein the diamondoid comprises a derivatized diamondoid.
- 10 54. The integrated circuit device of claim 52, wherein the diamondoid comprises an underivatized diamondoid.
 - 55. The integrated circuit device of claim 52, wherein the diamondoid is a lower diamondoid.
 - 56. The integrated circuit device of claim 52, wherein the diamondoid is a higher diamondoid.

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- 57. The integrated circuit device of claim 56, wherein the diamondoid is selected from the group consisting of tetramantane, pentamantane, hexamantane, heptamantane, octamantane, nonamantane, decamantane, and undecamantane.
 - 58. A method of nucleating the growth of a diamond film, wherein the film is nucleated with triamantane.
 - 59. A method of nucleating the growth of a diamond film, wherein the film is nucleated with a diamondoid selected from the group consisting of a lower diamondoid, a higher diamondoid, and a mixture of a lower and a higher diamondoid.
- 30 60. The method of claim 59, wherein the higher diamondoid is selected from the group consisting of tetramantane, pentamantane, hexamantane, heptamantane, octamantane, nonamantane, decamantane, and undecamantane.